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## **Listing of Claims**

The following listing of claims will replace all prior versions, and listings, of claims in the subject application:

Claim I (canceled).

- 2. (currently amended) The surface-emission laser diode as claimed in claim [[1]] 4, characterized in that at least a lower spacer layer and an upper spacer layer contains ln.
- 3. (currently amended) The surface-emission laser diode as claimed in claim [[1]] 4, characterized in that, in said second lower reflector, said low refractive index layer and said high refractive index layer are repeated by 10 pairs or less.
- 4. (currently amended) [[The]] ∆ surface-emission laser diode as elaimed in claim 1, characterized by:

a semiconductor substrate;

a cavity region formed over said semiconductor substrate, said cavity region comprising; an active layer structural part including at least one quantum well active layer producing a laser light and a barrier layer; and a spacer layer provided in a vicinity of said active layer structural part, said spacer layer comprising at least one material; and

an upper reflector and a lower reflector provided over said semiconductor substrate respectively at a top part and a bottom part of said cavity region.

said cavity region, said upper reflector and said lower reflector forming a mesa structure

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over said semiconductor substrate,

said upper reflector and said lower reflector constituting a semiconductor distributed

Bragg reflector having a periodic change of refractive index and reflecting an incident light by interference of optical waves.

at least a part of said semiconductor distributed Bragg reflector being formed of a layer of small refractive index of  $Al_xGa_{1-x}As$  (0<x<1) and a layer of large refractive index of  $Al_xGa_{1-x}As$  (0<x<1).

said lower reflector being formed of a first lower reflector baying a low-refractive index layer of AlAs and a second lower reflector formed on said first lower reflector, said second lower reflector having a low-refractive index layer of AlGaAs,

wherein any one layer constituting said cavity region contains In, and

in that a part of said spacer layer comprises  $(Al_uGa_{1-u})_bIn_{1-b}P$   $(0 < a \le 1, 0 \le b \le 1)$ , said quantum well active layer comprises  $Ga_cIn_{1-c}P_dAs_{1-d}$   $(0 \le c \le 1, 0 \le d < 1)$ , and said barrier layer comprises  $Ga_cIn_{1-c}P_fAs_{1-f}$   $(0 \le c \le 1, 0 \le f \le 1)$ .

- 5. (original) The surface-emission laser diode as claimed in claim 4, characterized in that said quantum well active layer has a compressive strain.
- 6. (original) The surface-emission laser diode as claimed in claim 5, characterized in that said barrier layer has a tensile strain.
- 7. (original) The surface-emission laser diode as claimed in claim 4, characterized in that said semiconductor substrate comprises a (100) GaAs substrate having a surface orientation

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inclined in a direction of a (111)A surface with an angle in a range of 5° to 20°.

8. (original) The surface-emission laser diode as claimed in claim 4, characterized in that said surface-emission laser diode has an oscillation wavelength of about 680nm or longer.

9. (original) The surface-emission laser diode as claimed in claim 5, characterized in that said semiconductor substrate comprises a (100) GaAs substrate having a surface orientation inclined in a direction of a (111)A surface by an angle in a range of 5° to 20°.

10. (original) The surface-emission laser diode as claimed in claim 5, characterized in that said surface-emission laser diode has an oscillation wavelength of about 680nm or longer.

Claims 11-35 (canceled).